

PROCEEDINGS OF SPIE

Laser-based Micro- and Nanoprocessing VIII

**Udo Klotzbach
Kunihiko Washio
Craig B. Arnold**
Editors

**4–6 February 2014
San Francisco, California, United States**

Sponsored and Published by
SPIE

Volume 8968

Proceedings of SPIE 0277-786X, V. 8968

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Laser-based Micro- and Nanoprocessing VIII, edited by Udo Klotzbach, Kunihiko Washio, Craig B. Arnold,
Proc. of SPIE Vol. 8968, 896801 · © 2014 SPIE · CCC code: 0277-786X/14/\$18 · doi: 10.1117/12.2063206

Proc. of SPIE Vol. 8968 896801-1

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Author(s), "Title of Paper," in *Laser-based Micro- and Nanoprocessing VIII*, edited by Udo Klotzbach, Kunihiko Washio, Craig B. Arnold, Proceedings of SPIE Vol. 8968 (SPIE, Bellingham, WA, 2014) Article CID Number.

ISSN: 0277-786X

ISBN: 9780819498816

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445

SPIE.org

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Printed in the United States of America.

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